

**Application:** Clean room environment, automated production

lines for semiconductor plants

**Current challenges:** The broad area of plants, the inconvenient access to

clean rooms

Incapable of centralized and remote control of the

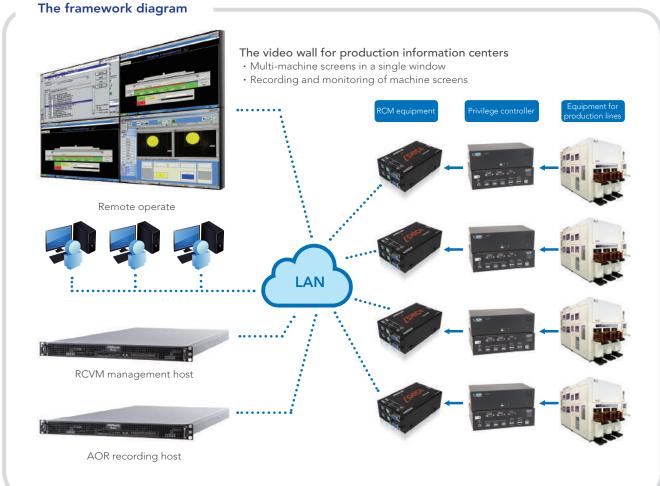
system, no open API

Installed software occupies the system resource of  $% \left\{ 1,2,\ldots ,n\right\}$ 

machines

Prevent the leakage of production data for machines

## RCVM Remote Monitoring System The framework diagram



## The benefits of introducing RCVM System

Reduce time for personnel to move among different plants, centralized control of machines for equipment, real-time monitor of split machine screens;

Provide API integration and customized functions, increase the man to machine ratio, increase the equipment availability;

Replay machine screens to determine problems, and monitor screens for site environment.